

# Sangwoo Lee

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/11411033/publications.pdf>

Version: 2024-02-01

11  
papers

362  
citations

1478505

6  
h-index

1588992

8  
g-index

11  
all docs

11  
docs citations

11  
times ranked

212  
citing authors

#	ARTICLE	IF	CITATIONS
1	Vibration-induced errors in MEMS tuning fork gyroscopes. Sensors and Actuators A: Physical, 2012, 180, 32-44.	4.1	65
2	DRY AND WET ETCHING WITH (111) SILICON FOR HIGH-PERFORMANCE MICRO AND NANO SYSTEMS. International Journal of Computational Engineering Science, 2003, 04, 181-187.	0.1	2
3	Surface/bulk micromachined single-crystalline-silicon micro-gyroscope. Journal of Microelectromechanical Systems, 2000, 9, 557-567.	2.5	84
4	A New Micromachining Technique with (111) Silicon. Japanese Journal of Applied Physics, 1999, 38, 2699-2703.	1.5	32
5	Mesa-supported, Single-crystal Microstructures Fabricated by the Surface/Bulk Micromachining Process. Japanese Journal of Applied Physics, 1999, 38, 4244-4249.	1.5	25
6	The surface/bulk micromachining (SBM) process: a new method for fabricating released MEMS in single crystal silicon. Journal of Microelectromechanical Systems, 1999, 8, 409-416.	2.5	115
7	The effects of post-deposition processes on polysilicon Young's modulus. Journal of Micromechanics and Microengineering, 1998, 8, 330-337.	2.6	22
8	The Effects of Texture and Doping on The Young's Modulus of Polysilicon. Materials Research Society Symposia Proceedings, 1998, 518, 21.	0.1	5
9	A New Micromachining Technology Using. , 1998, , .		1
10	Electrostatic actuation of surface/bulk micromachined single-crystal silicon microresonators. , 0, , .		2
11	Surface/bulk micromachining (SBM) process and deep trench oxide isolation method for MEMS. , 0, , .		9